



PATENT

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Rosengaus et al.

Attorney Docket No.: KLA1P001C1

Application No.: 09/474,941

Examiner: Rosenberger, R.

Filed: December 30, 1999

Group: 2877

Title: SYSTEM AND METHOD FOR  
INSPECTING SEMICONDUCTOR  
WAFERS

## CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Box Non-Fee Amendment Commissioner for Patents, Washington, DC 20231 on January 9, 2001.

Signed: \_\_\_\_\_

Laura M. Dean

Box Non-Fee Amendment  
Commissioner for Patents  
Washington, DC 20231

Sir:

Transmitted herewith is an Amendment in the above-identified application.

The fee has been calculated as shown below.

	Claims Remaining After Amendment	Highest Previously Paid For	Present Extra	SMALL ENTITY RATE FEE	LARGE ENTITY RATE FEE
TOTAL CLAIMS	<u>18</u> -	<u>22</u>	<u>0</u>	X 9 = \$	OR X18 = \$0
INDEP CLAIMS	<u>4</u> -	<u>4</u>	<u>0</u>	X40 = \$	OR X80 = \$0
[ ] Multiple Dependent Claim Present and Fee Not Previously Paid				\$135=\$0	\$270= \$0
TOTAL				\$_____	\$0

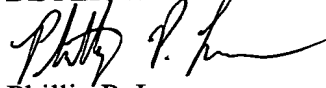
- ☐ Applicant(s) hereby petition for a \_\_\_\_\_(s) extension of time to respond to the aforementioned Office Action .
- ☒ Applicant(s) believe that no (additional) Extension of Time is required; however, if it is determined that such an extension is required, Applicant(s) hereby petition that such an extension be granted and authorize the Commissioner to charge the required fees for an Extension of Time under 37 CFR 1.136 to Deposit Account No. 50-0388.
- ☐ Enclosed is our Check No. \_\_\_\_\_ in the amount of \$\_\_\_\_\_ to cover the additional claim fee and/or extension of time fees.
- ☒ Enclosed is an Associate Power of Attorney for this application.

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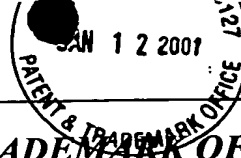
Please charge the required fees, or any additional fees required to facilitate filing the enclosed response, to Deposit Account No. 50-0388 (Order No.KLA1P001C1). A copy of this sheet is enclosed.

Respectfully submitted,  
BEYER WEAVER & THOMAS, LLP



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Printed Name: Laura M. Dean

Signed: \_\_\_\_\_

*Laura M. Dean*

AMENDMENT B

Box Non-Fee Amendment  
Commissioner for Patents  
Washington, D.C. 20231

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Dear Sir:

In response to the Office Action dated October 12, 2000, a response to which is due January 12, 2000, please enter the following amendments and consider the following remarks.

IN THE CLAIMS:

Please CANCEL claims 3 and 8 without prejudice or disclaimer.

Please AMEND claims 1, 4, 6, and 17 as follows:

1. (Three Times Amended) An integrated circuit manufacturing system comprising:
- (a) a plurality of interrelated integrated circuit manufacturing tools capable of operating in parallel on a plurality of semiconductor wafers, wherein the plurality of interrelated integrated circuit manufacturing tools comprise a cluster tool;